What is claimed is:

1. A thin-film magnetic head material including: a plurality of rows of head-to-be sections to be thin-film magnetic heads; an inter-row cutting section provided to be a position at which adjacent ones of the rows are to be separated; and an intra-row cutting section provided to be a position at which adjacent ones of the head-to-be sections in each of the rows are to be separated; the head material comprising:

a detection element to be used for detecting an amount of processing when specific processing is performed on the head material;

an electrode formed in the inter-row cutting section for electrically connecting the detection element to an external device; and

a conductor for electrically connecting the electrode to the detection element.

- 2. The head material according to claim 1, wherein the detection element and the conductor are formed in the intra-row cutting section.
- 3. A method of manufacturing a thin-film magnetic head material, the head material including: a plurality of rows of head-to-be sections to be thinfilm magnetic heads; an inter-row cutting section provided to be a position at which adjacent ones of the rows are to be separated; and an intra-row cutting section provided to be a position at which adjacent ones of the head-to-be sections in each of the rows are to be separated; the method including the steps of:

providing a detection element to be used for detecting an amount of processing when specific processing is performed on the head material; an electrode for electrically connecting the detection element to an external device; and a conductor for electrically connecting the electrode to the detection element, and

forming the electrode in the inter-row cutting section.

- 4. The method according to claim 3, wherein the detection element and the conductor are formed in the intra-row cutting section.
- 5. A method of manufacturing thin-film magnetic heads through the use of a thin film magnetic head material including: a plurality of rows of head-to-be sections to be thin-film magnetic heads; an inter-row cutting section provided to be a position at which adjacent ones of the rows are to be separated; and an intra-row cutting section provided to be a position at which adjacent ones of the head-to-be sections in each of the rows are to be separated; the method including the steps of:

fabricating the head material including: a detection element to be used for detecting an amount of processing when specific processing is performed on the head material; an electrode formed in the inter-row cutting section for electrically connecting the detection element to an external device; and a conductor for electrically connecting the electrode to the detection element;

performing the specific processing on the head material while monitoring an output signal of the detection element obtained through the electrode;

forming a head aggregate including one of the rows of the head-to-be sections by separating the head material having gone through the step of performing the processing at the inter-row cutting section; and

forming the thin-film magnetic heads by separating the head aggregate formed in the step of forming the head aggregate at the intra-row cutting section.

6. The method according to claim 5, wherein the detection element and the conductor are formed in the intra-row cutting section in the step of manufacturing the head material.